

<b>Notice of References Cited</b>	Application/Control No. 10/501,268		Applicant(s)/Patent Under Reexamination GUILLERMO ET AL.	
	Examiner Denise B. Anderson		Art Unit 2877	Page 1 of 1

#### U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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	B	US-			
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	E	US-			
	F	US-			
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	J	US-			
	K	US-			
	L	US-			
	M	US-			

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#### NON-PATENT DOCUMENTS

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	U	Erdelyi et al. "Generation of diffraction-free beams for applications in optical microlithography", J. Vac. Sci. Technol. B 15 (2), Mar/Apr 1997, pp. 287-292.
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.